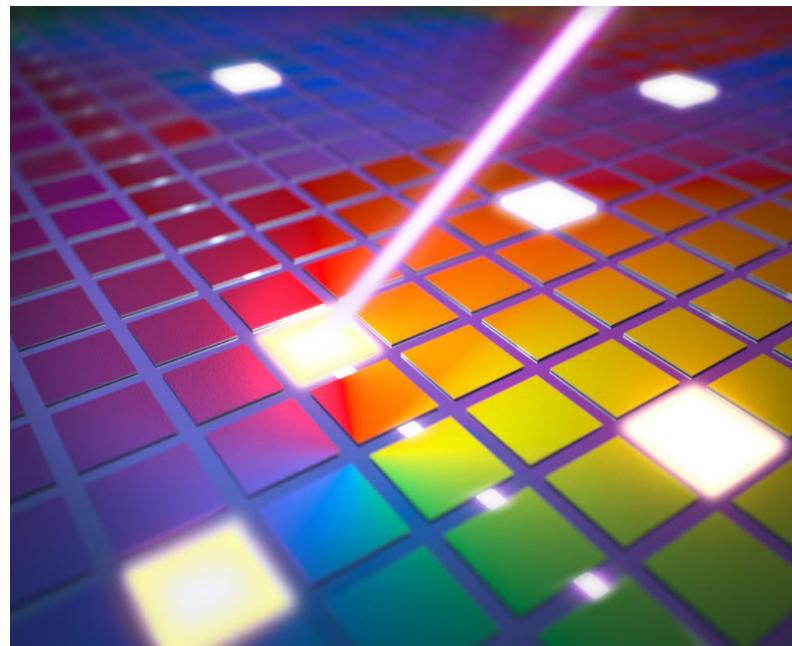


Real-time autonomous combinatorial experimentation: from atomic layer deposition to metal additive manufacturing



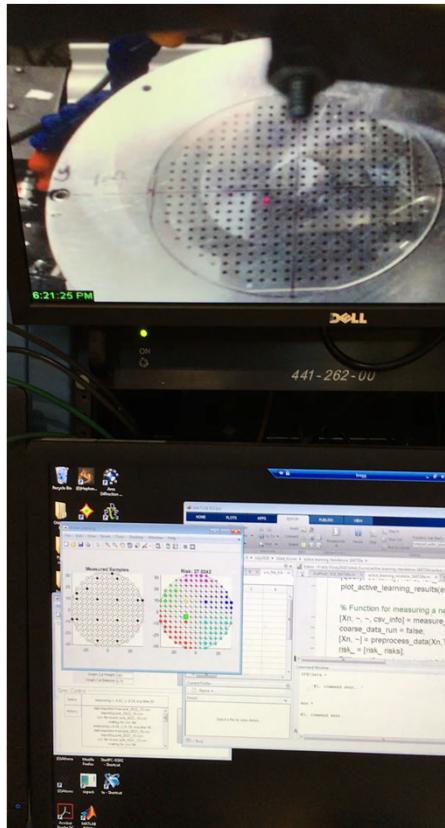
**Ichiro Takeuchi
University of Maryland**



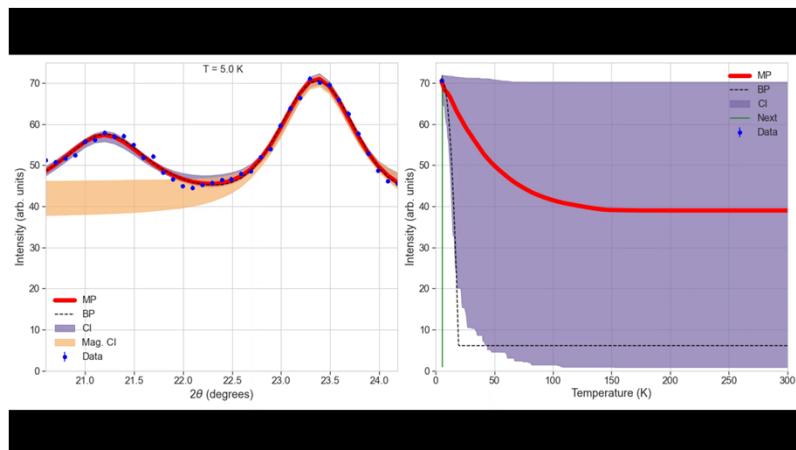


Live autonomous closed-loop materials science

w/ G. Kusne, A. McDannald (NIST)



CAMEO: Closed-loop autonomous materials exploration and optimization
Nature Communications 11, 5966 (2020)

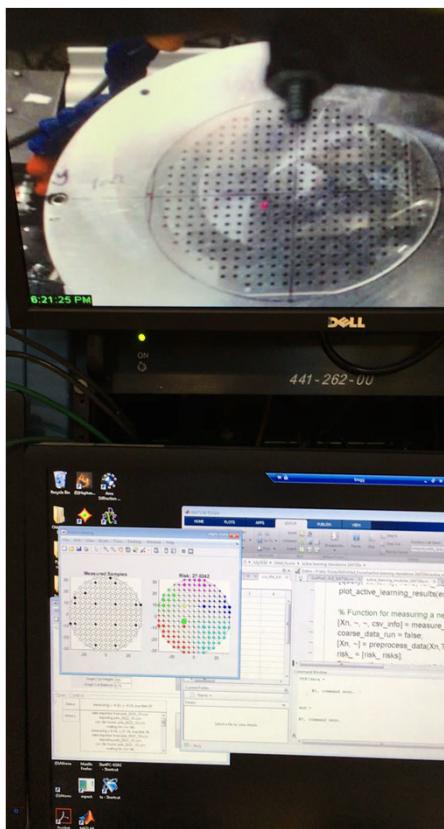


Autonomous neutron diffraction explorer (ANDiE)
Applied Physics Reviews 9, 021408 (2022)



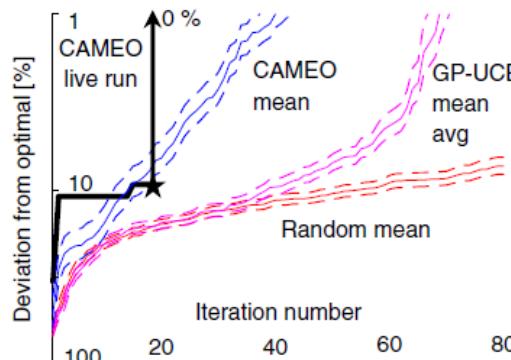
LEGOLAS: LEGO based Low-cost Autonomous System for Education
MRS Bulletin 47, 881 (2022)

Autonomous combinatorial experimentation: materials discovery via Bayesian active learning



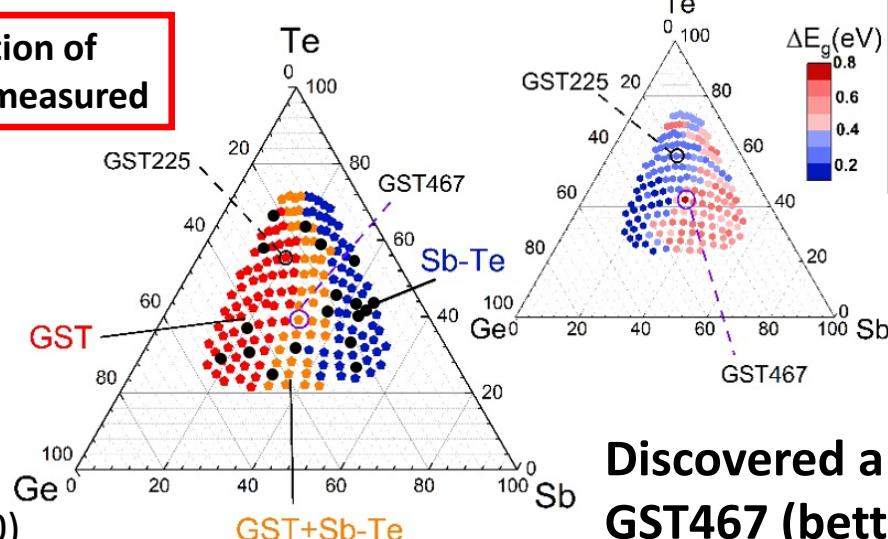
Remote diffraction at SLAC

Nature Communications 11, 5966 (2020)



Performs phase map and property optimization together

Only a fraction of points are measured



Discovered a new PCM material,
GST467 (better than GST225)

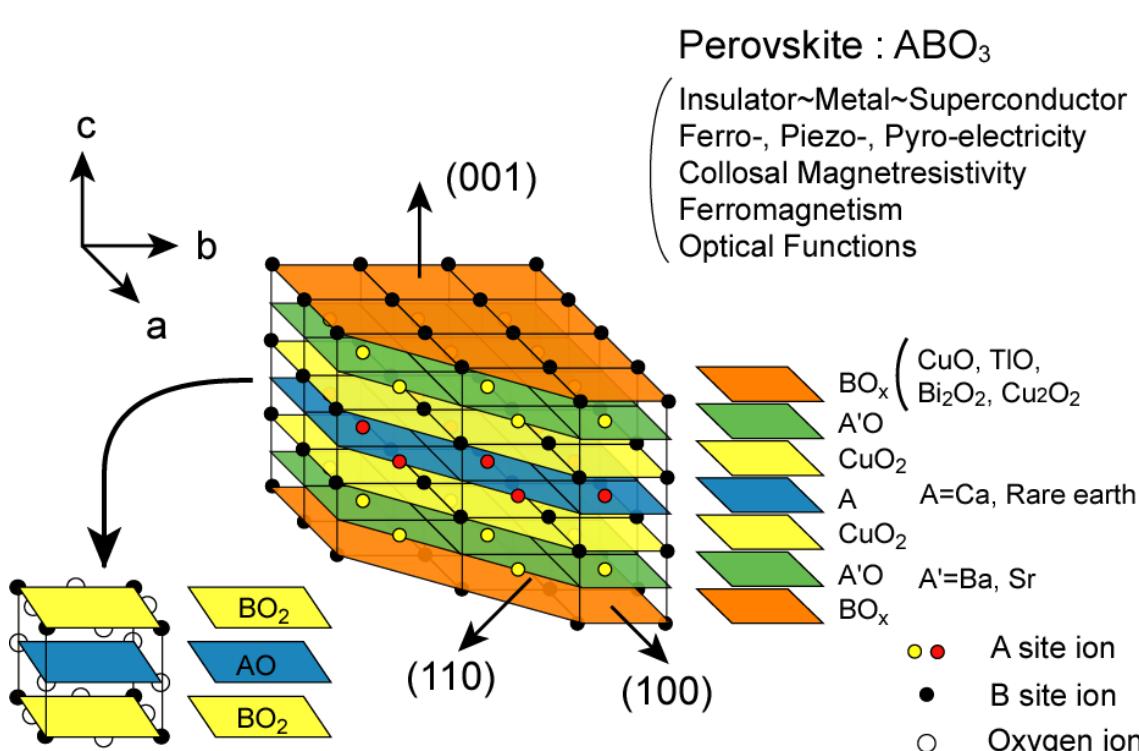
**Patent sponsored
by SRC**

**Reproduced in
multiple labs
including industry**

Wu et al., Nat.
Commun. 15, 13 (2024)

Autonomous atomic-layer synthesis

w/ Haotong Liang (UMD), Yunlong Sun (U. Tokyo), Mikk Lippmaa (U. Tokyo)



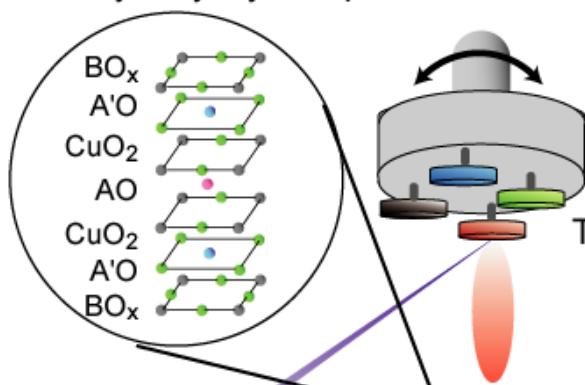
Pulsed laser deposition for creating new materials and tune properties by controlling atomic arrangement at unit-cell level



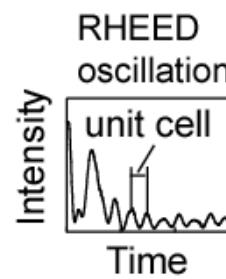
Autonomous atomic-layer synthesis

w/ Haotong Liang (UMD), Yunlong Sun (U. Tokyo), Mikk Lippmaa (U. Tokyo)

Atomic layer by layer deposition



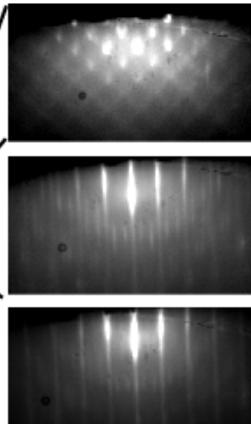
Targets



UV laser

electron beam

Substrate
Shadow masks



Atomic-level synthesis

Structure determination

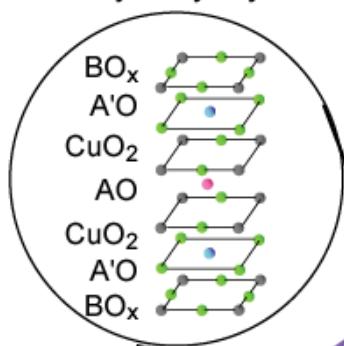
Pulsed laser deposition for creating new materials and tune properties by controlling atomic arrangement at unit-cell level

Combinatorial pulsed laser deposition circa. 2000

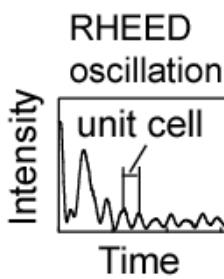
Autonomous atomic-layer synthesis

w/ Haotong Liang (UMD), Yunlong Sun (U. Tokyo), Mikk Lippmaa (U. Tokyo)

Atomic layer by layer deposition



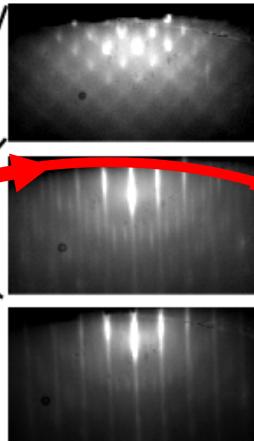
Targets



UV laser

electron beam

Substrate
Shadow masks



Atomic-level synthesis

Structure determination

Pulsed laser deposition for creating new materials and tune properties by controlling atomic arrangement at unit-cell level

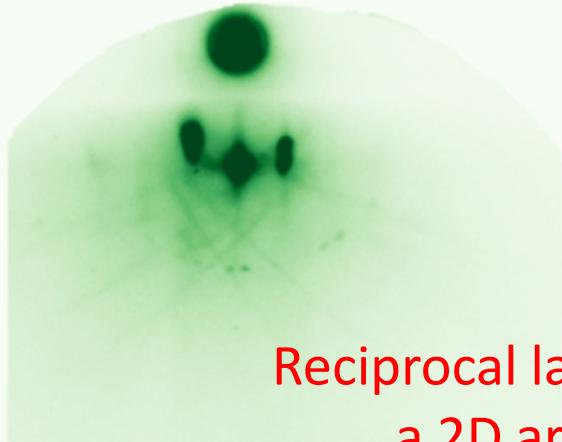
Combinatorial pulsed laser deposition circa. 2000

Live autonomous cycle (2023)

ML analysis of RHEED patterns

Bayesian optimization

RHEED is useful for understanding surface structures



Reciprocal lattice vector G is
a 2D array of rods



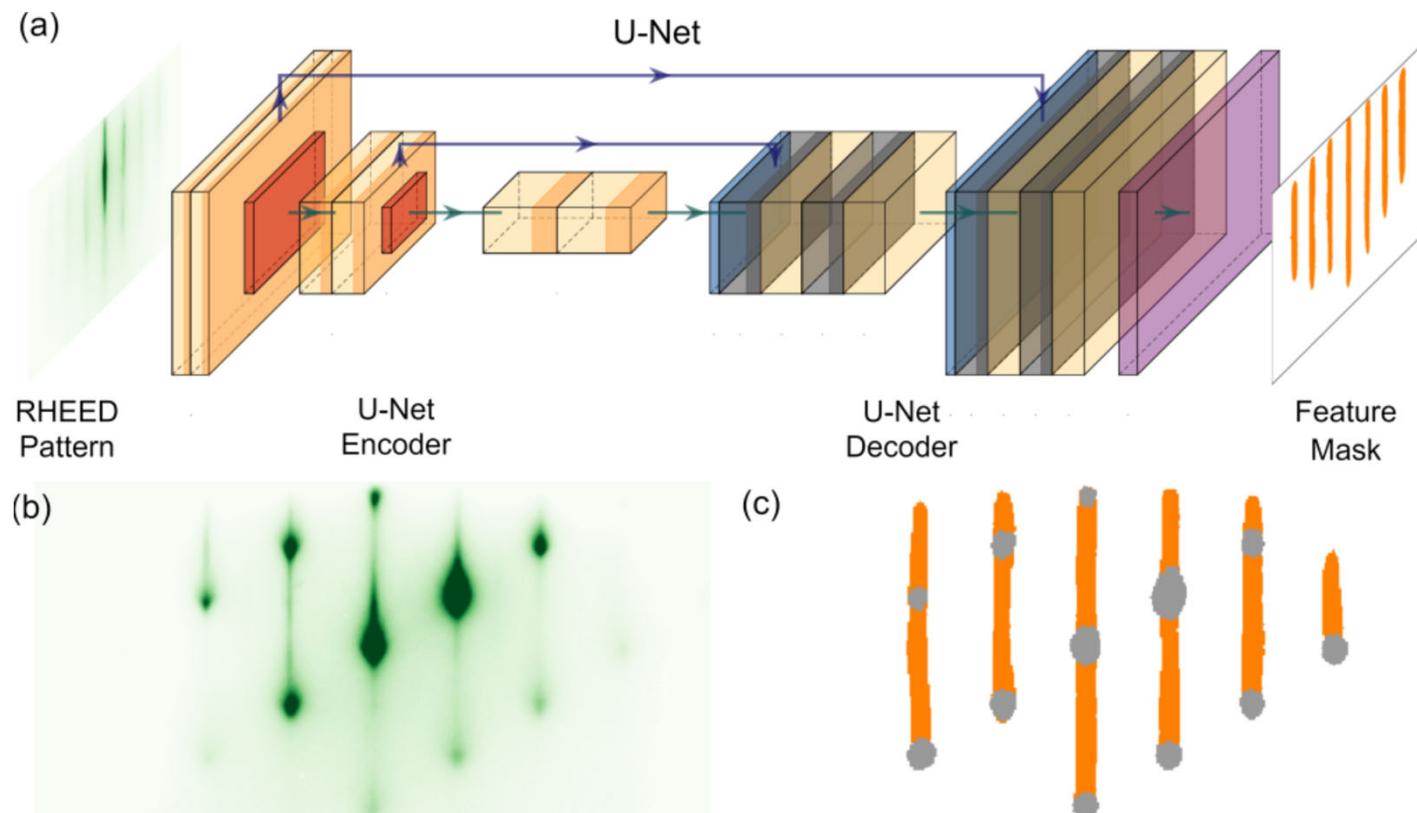
- Spotty pattern
- Kikuchi line (secondary scattering)
- Atomically **flat** surface

- Streaky pattern
- Common in MBE
- Disorder in the atomic-scale

- Streaky + spotty pattern:
3D structures
- Transmission patterns: 3D structure mixed with 2D structure

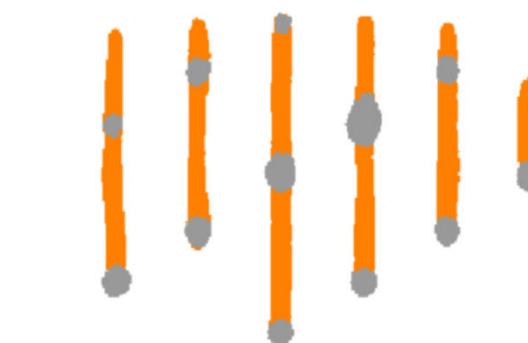
.....but it's usually for qualitative characterization

Quantitative live analysis of RHEED patterns using ML



Liang et al., Phys. Rev. Mat. 6, 063805 (2022)

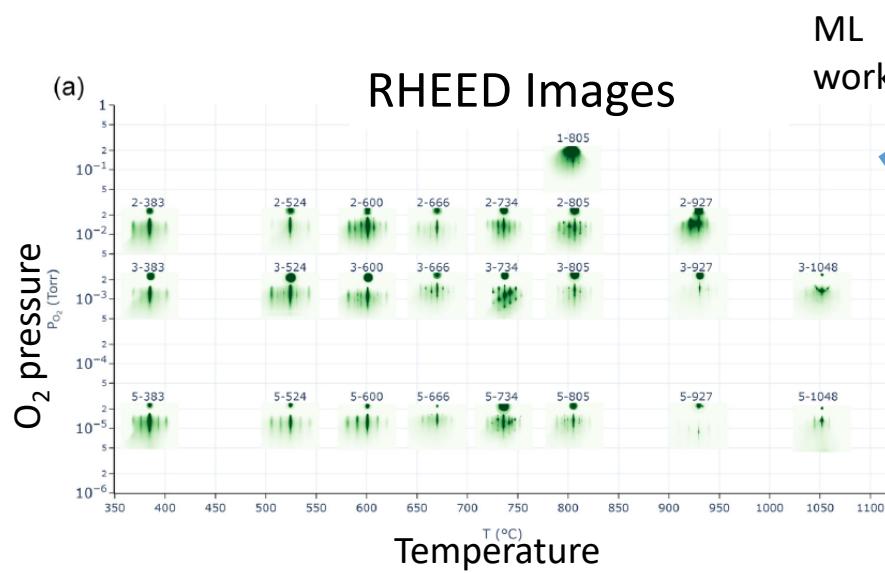
(c)



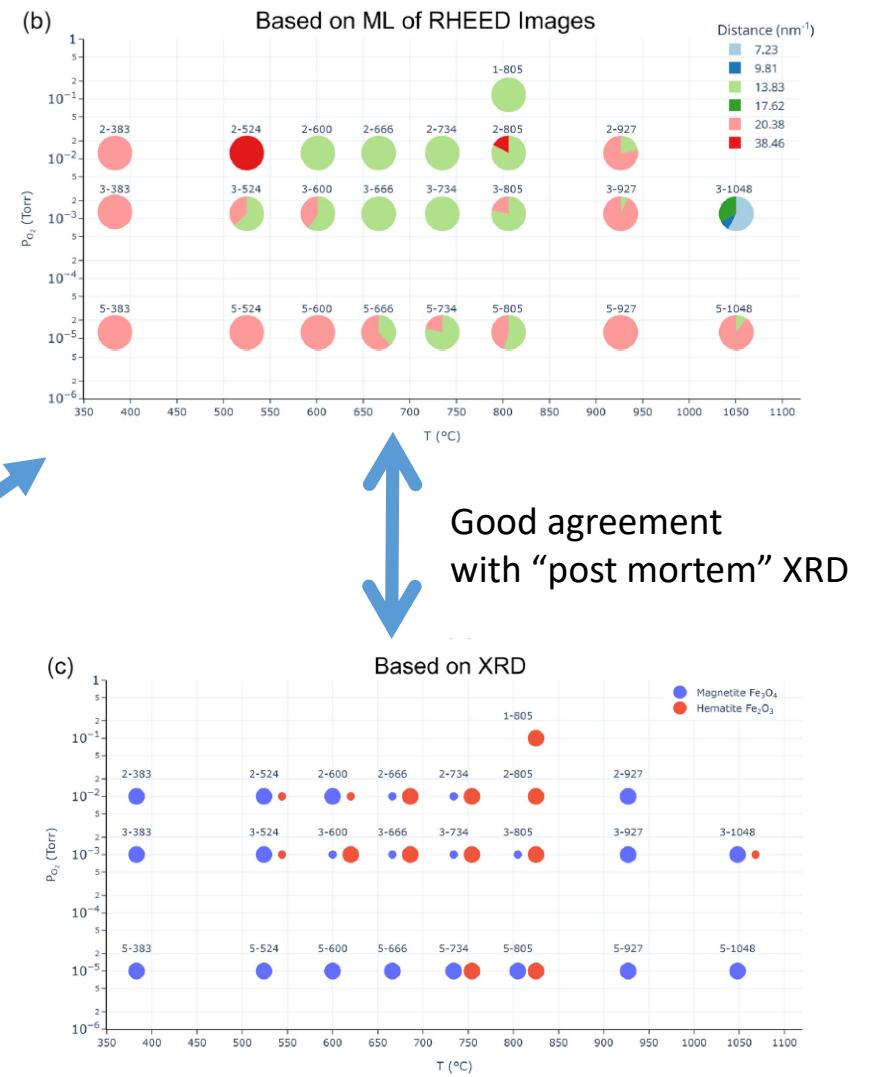
Other ML work on RHEED:
Vasudevan et al., ACS Nano 8, 10899 (2014);
Provence et al., Phys. Rev. Materials 4, 083807 (2020).

Quantitative analysis of RHEED patterns using ML

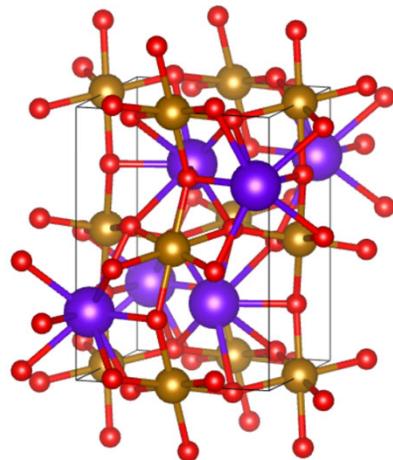
Growth phase map of FeO_x thin films:
 Fe_2O_3 vs Fe_3O_4 vs... as functions of O_2
 pressure and temperature during growth



Liang et al., Phys. Rev. Mat. 6, 063805 (2022)

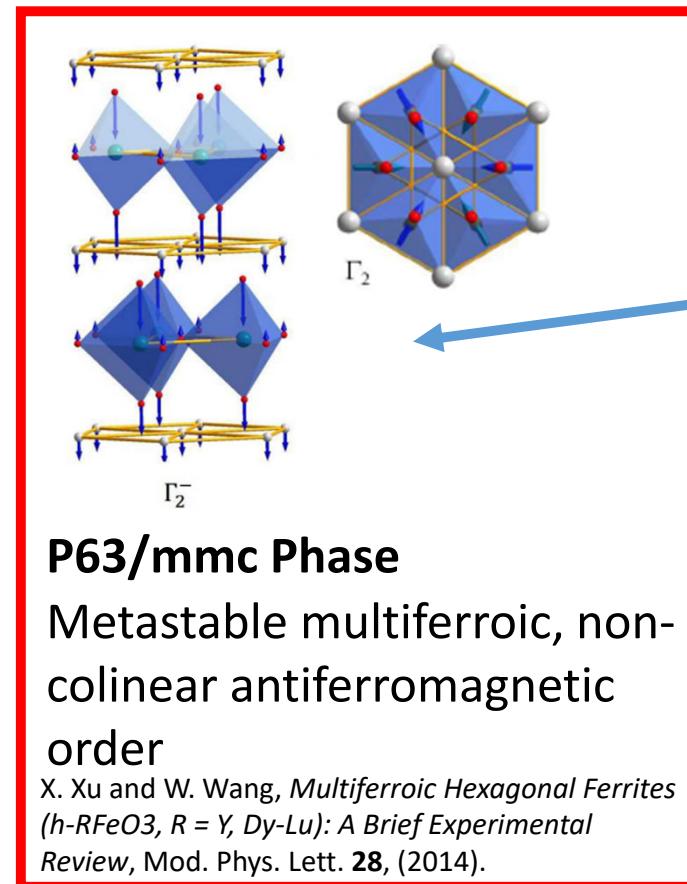


Target material: metastable hexagonal TbFeO_3



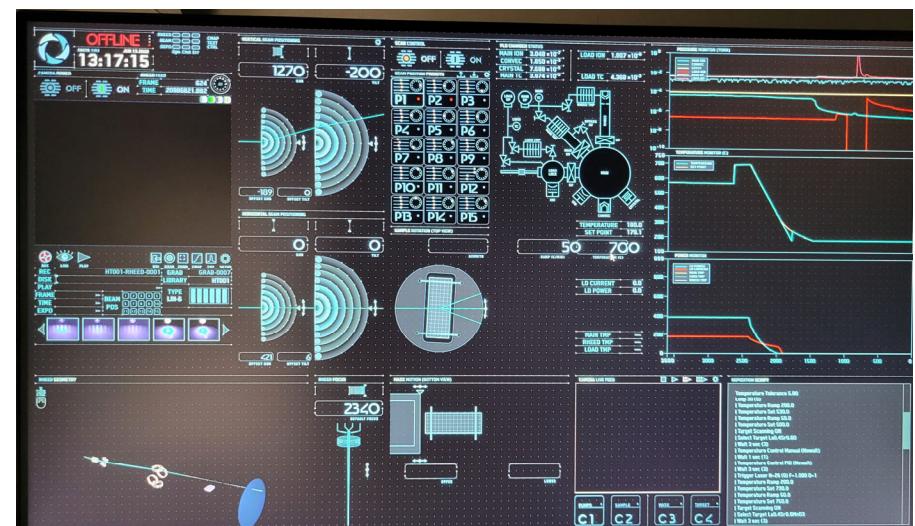
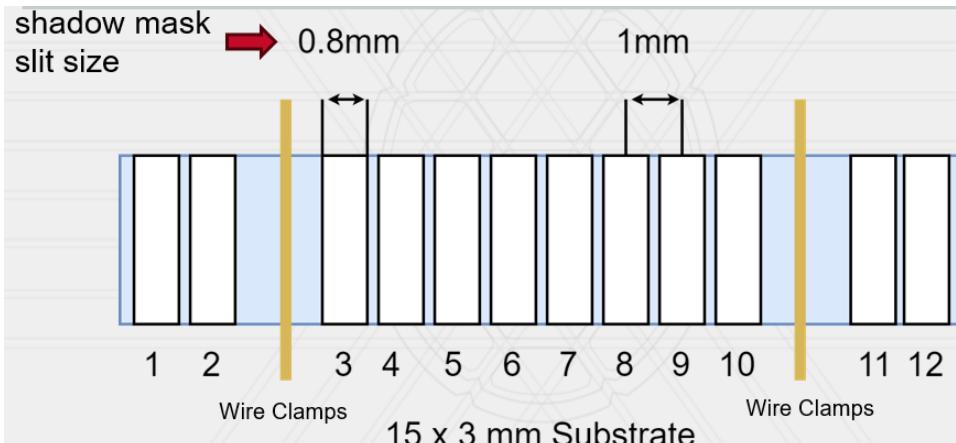
Pbnm Phase

Stable structure
colinear antiferromagnetic
order

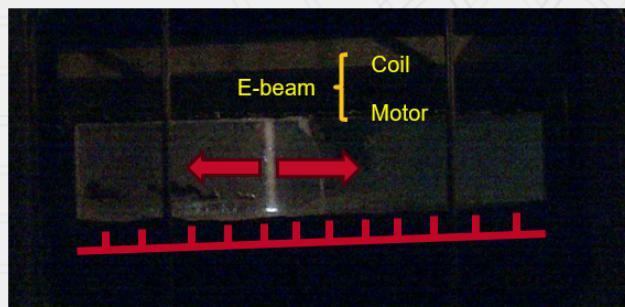


- Stabilize metastable hexagonal P63/mmc
- Search for optimal growth condition for thin films

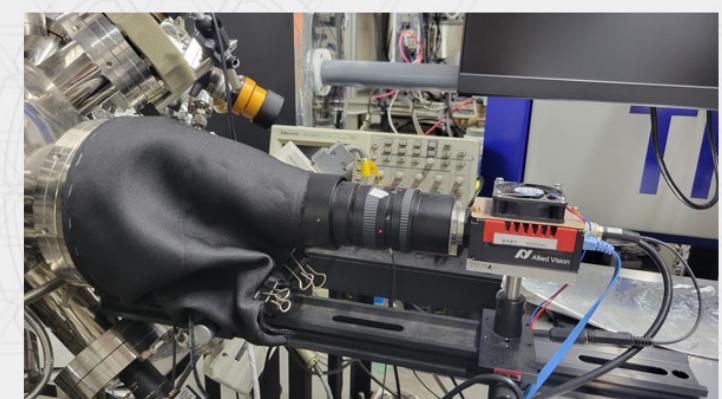
Autonomous atomic-layer synthesis setup 2023



Calibration



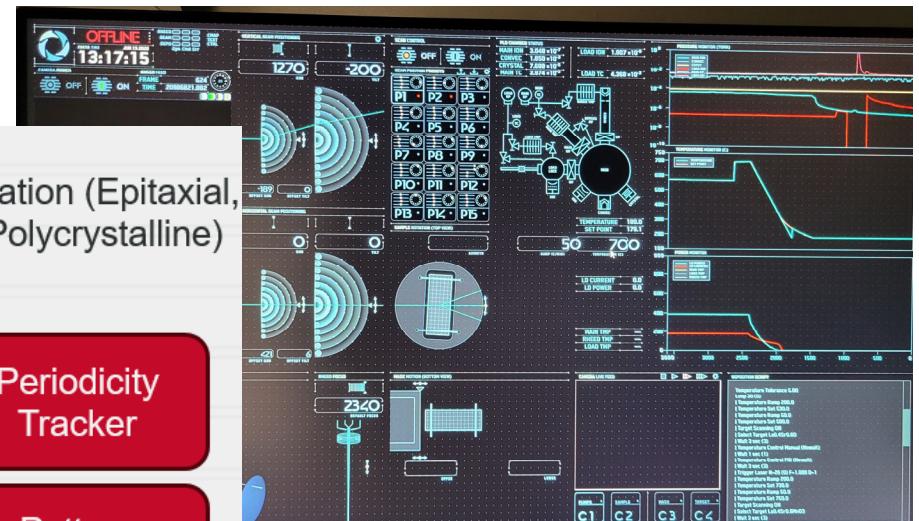
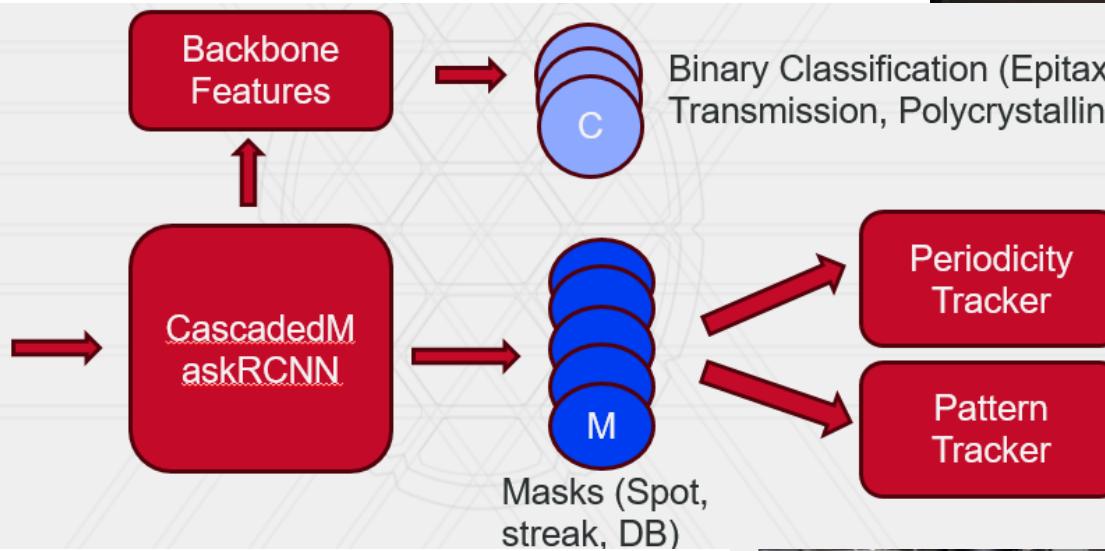
Low-light sensitive Camera (ELP)



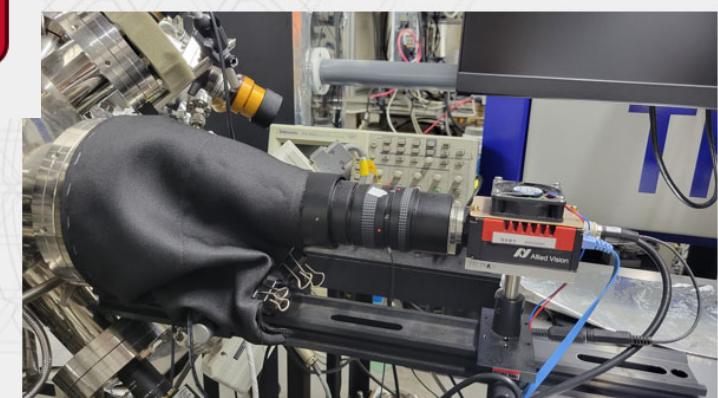
High Speed Network Camera (Allied Vision)

Autonomous atomic-layer synthesis setup 2023

New RHEED analysis pipeline



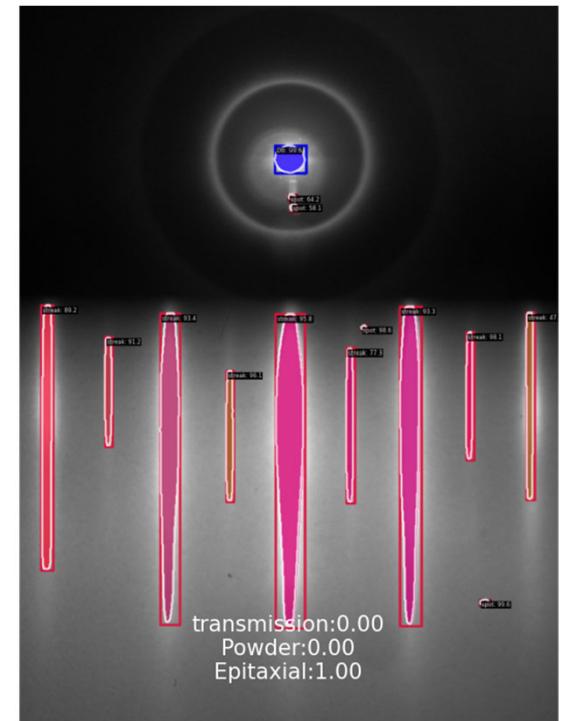
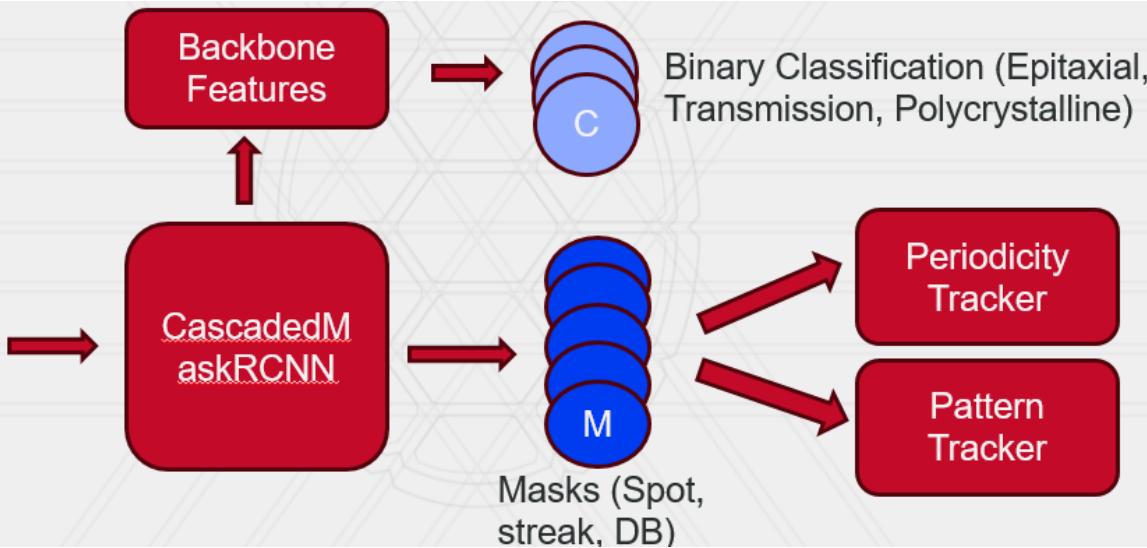
Low-light sensitive Camera (ELP)



High Speed Network Camera (Allied Vision)

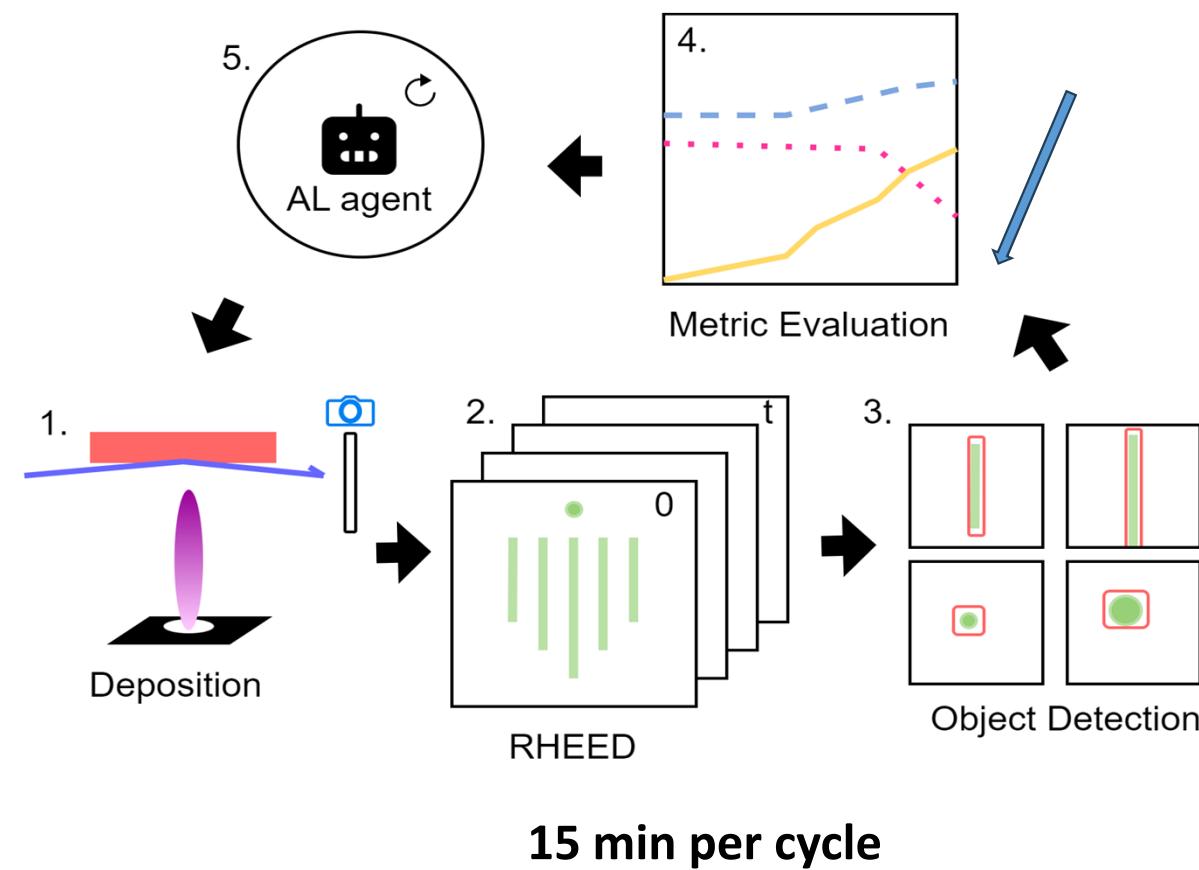
Autonomous atomic-layer synthesis setup 2023

New RHEED analysis pipeline



- Multiple features are identified: epitaxial vs islands vs ring (polycrystalline)
- Sharpness of the peak
- Periodicity gives us the lattice constant – can identify the phase

Autonomous live experimental loop for controlled growth of hexagonal TbFeO₃

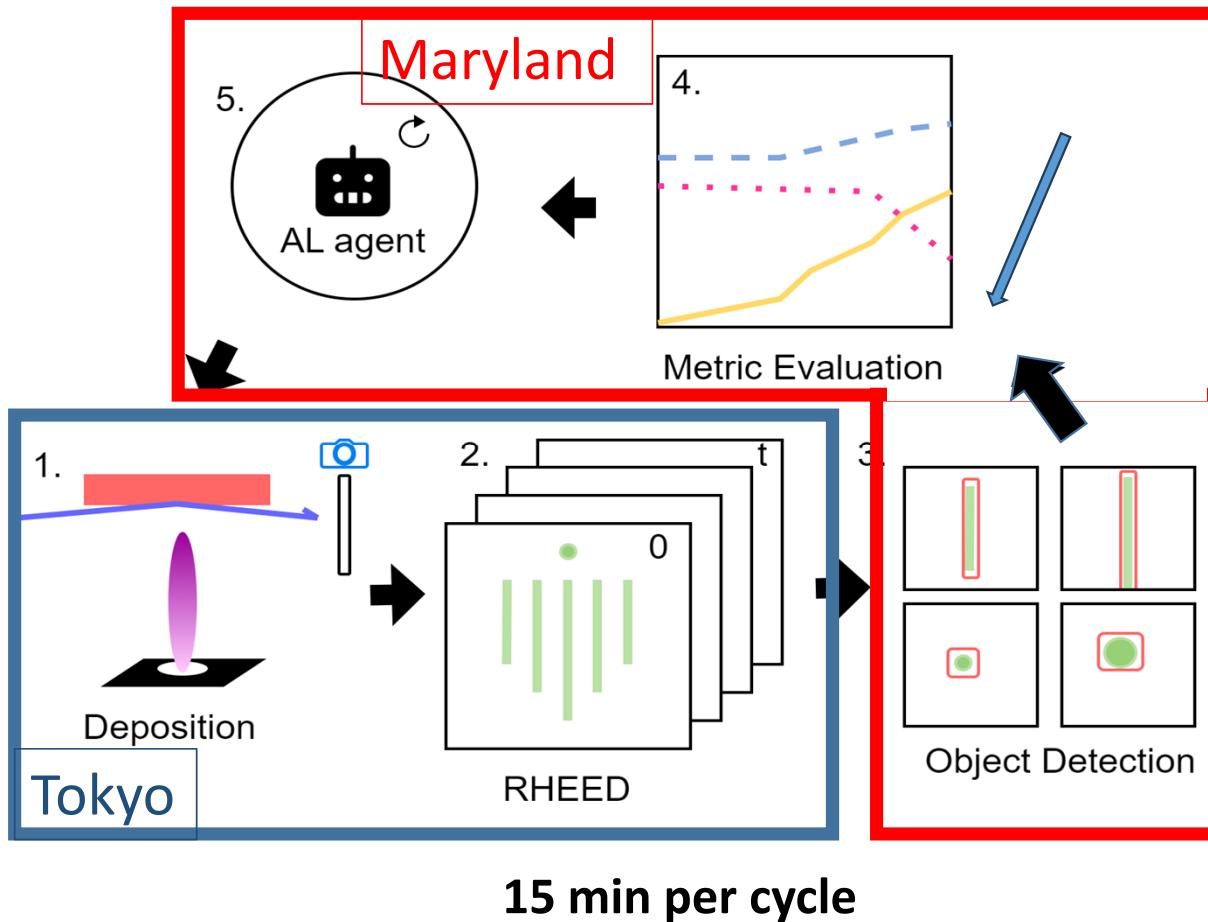


Parameters:

- O₂ pressure: 10⁻⁷-10⁻⁴ Torr (10 increments)
- Temperature: 600 – 1000 °C (16 increments)
- Laser pulse rate: 0.5 – 20 Hz (7 increments)

Total grid: 1100 experiments

Autonomous live experimental loop for controlled growth of hexagonal TbFeO₃

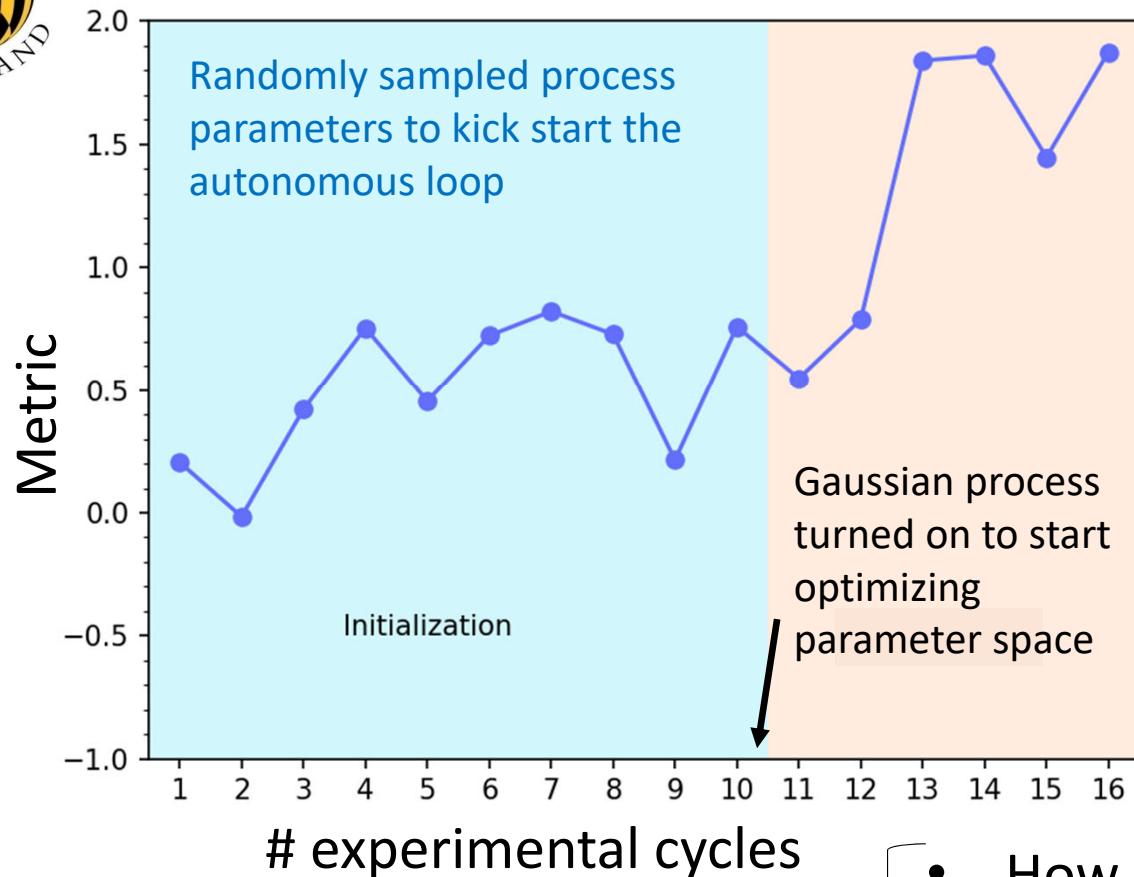


Parameters:

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Autonomous atomic-layer synthesis of TbFeO_3



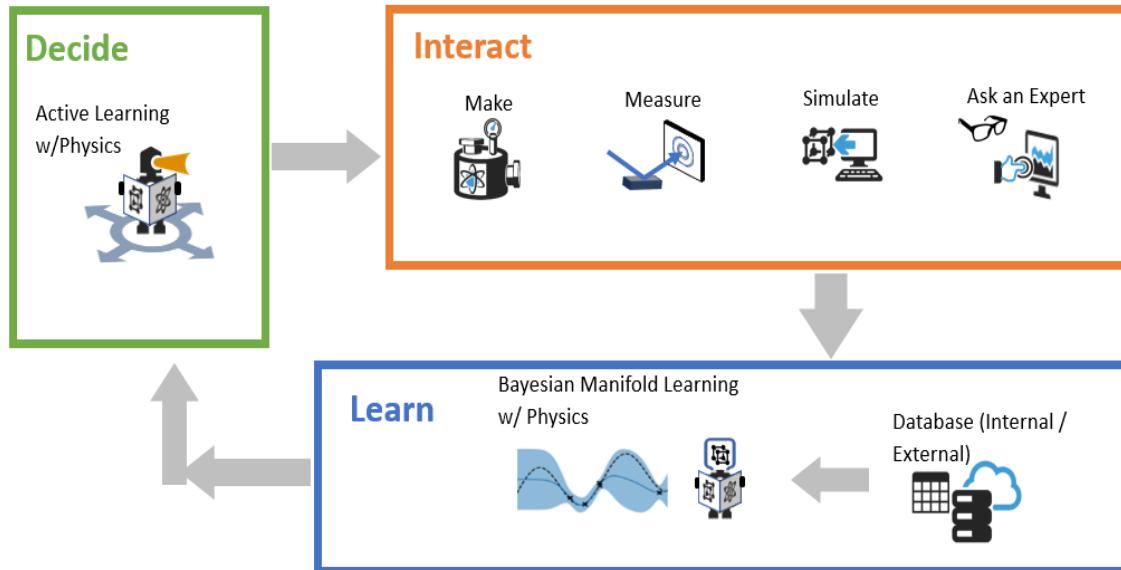
3 figures of merit from RHEED analysis combined into 1 metric ($-1 < \text{range} < 2$)

- How long does the phase stay stable?
- Sharpness of the peak
- How fast can we grow it? (Hz)

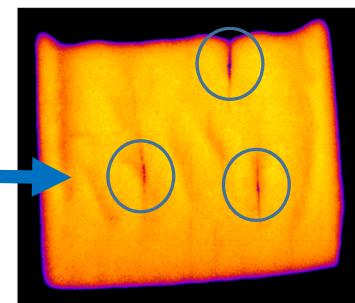
- 3 deposition parameters (pressure, temperature, dep rate: 1100 possibilities)
- Each cycle ~ 15 min
- Takes us to unexpected region of parameter space
- Always converges after only < 15 cycles of autonomous iteration

Autonomous additive manufacturing

Haotong Liang, J-C Zhao (MSE), Huapeng Huang (AAL)



Optical image
of a printed
superalloy



In-situ X-ray image
detects defects not
visible optically



(LDED tool)

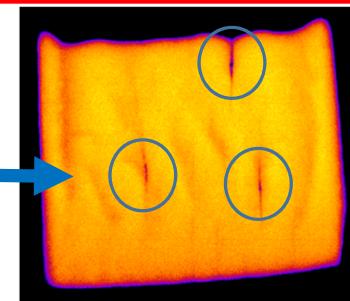
Compact X-ray
source and
detector mounted
inside printer

Autonomous additive manufacturing

Haotong Liang, J-C Zhao (MSE), Huapeng Huang (AAL)

Goal: develop a live closed-loop metal AM tool, which automatically evaluates the quality of printed materials, figures out how to optimize, and proceeds to find the best process conditions with minimum # of iterations w/ no human intervention

Optical image of a printed superalloy



In-situ X-ray image detects defects not visible optically

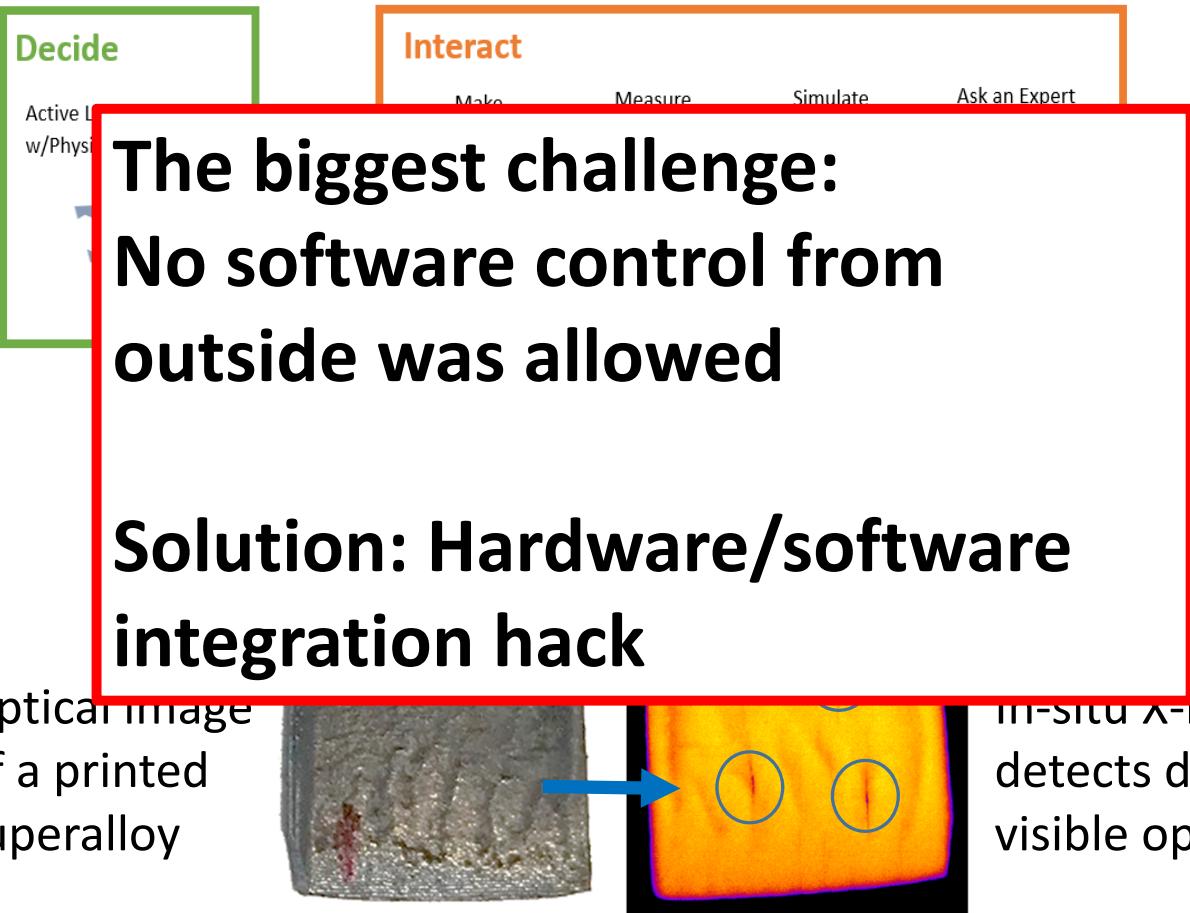


(LDED tool)

Compact X-ray source and detector mounted inside printer

Autonomous additive manufacturing

Haotong Liang, J-C Zhao (MSE), Huapeng Huang (AAL)



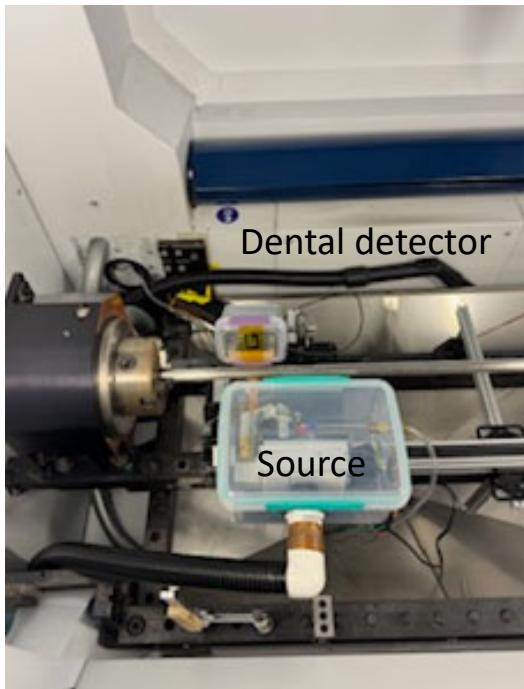
Compact X-ray source and detector mounted inside printer

Autonomous additive manufacturing

Haotong Liang, J-C Zhao (MSE), Huapeng Huang (AAL)

Hardware/software integration hack

Compact X-ray source and detector Camera for monitoring



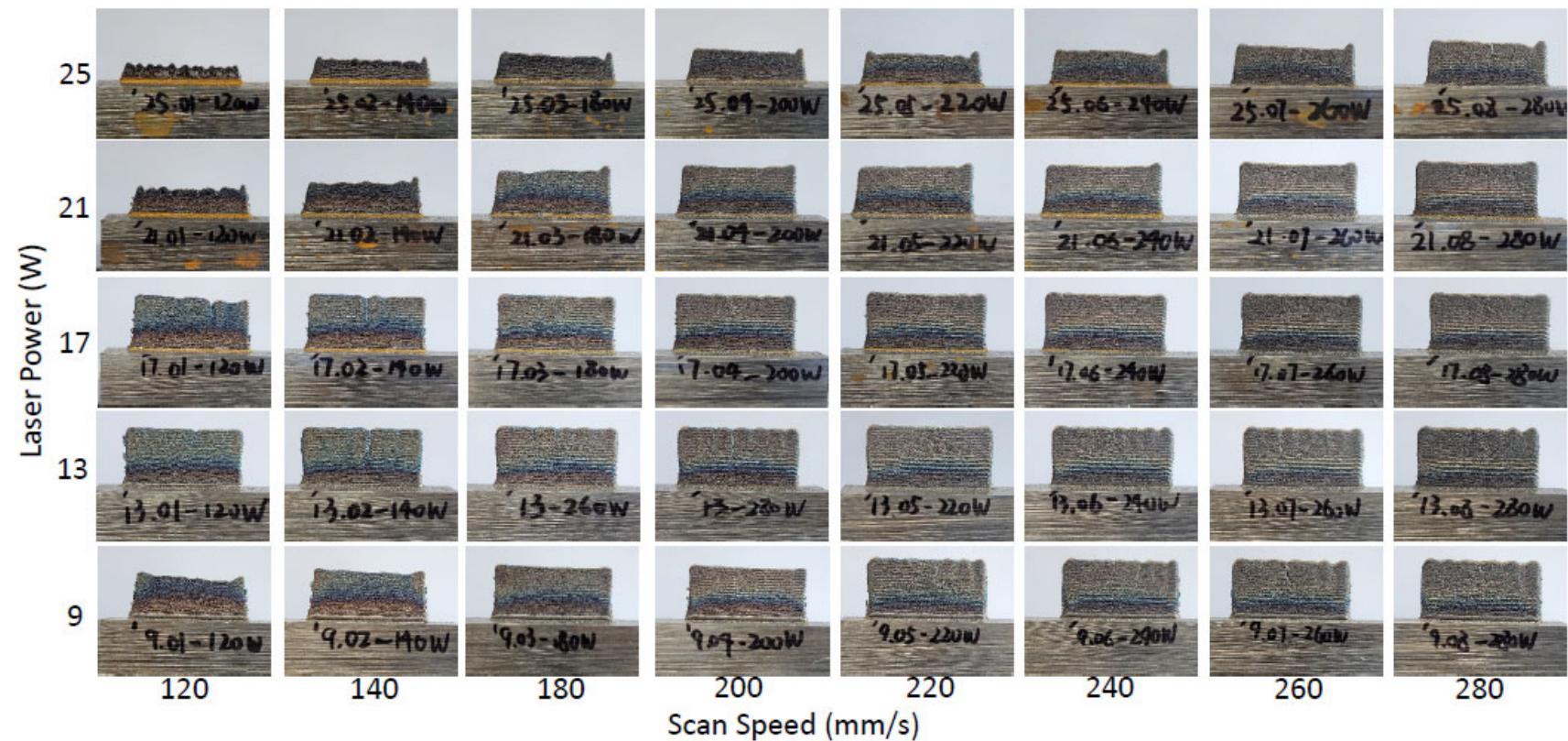
Motor and actuators to replace a knob and on/off button



Superalloy (MAR-M247) printing: minimize crack formation by controlling laser power and scan speed

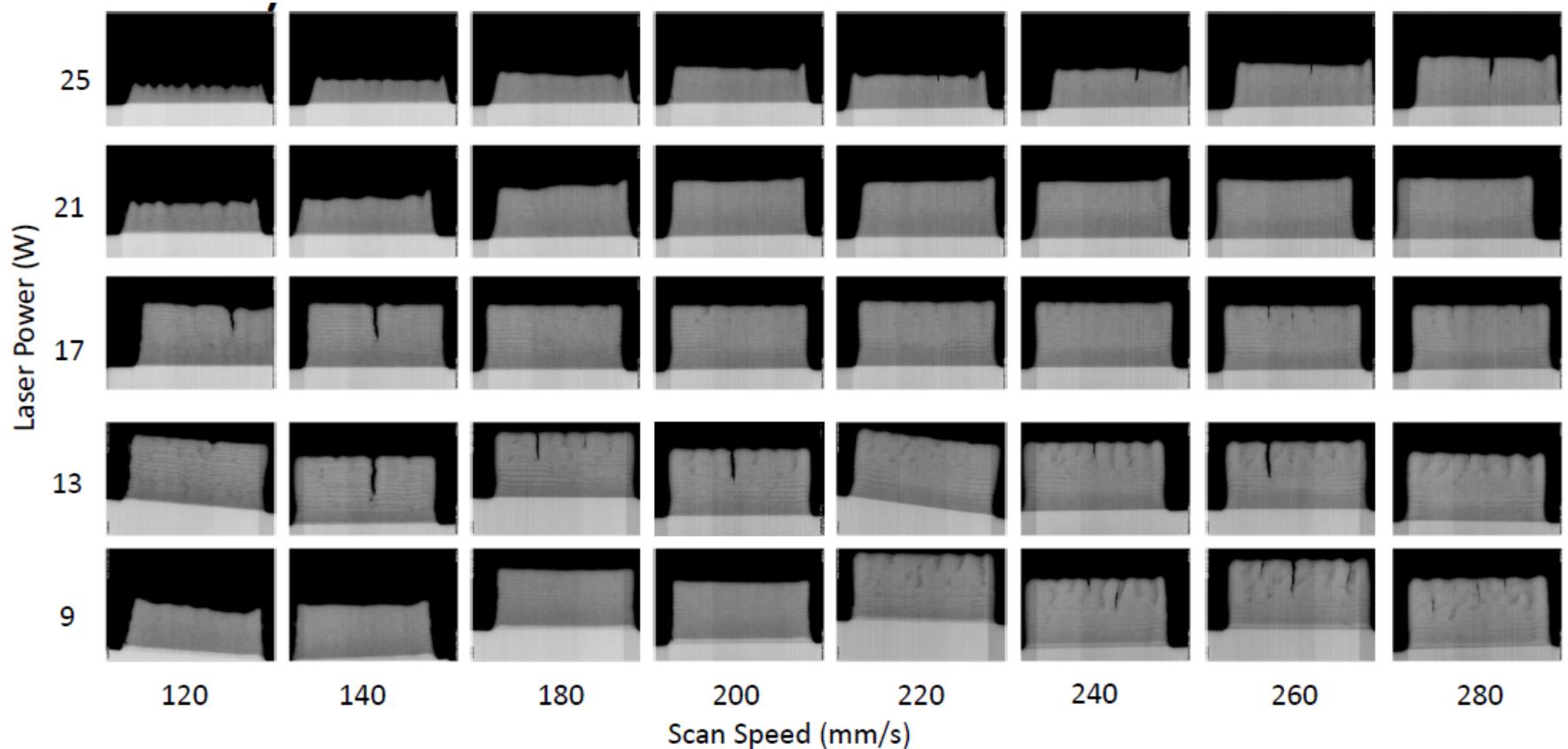


Reality check: grid measurements: optical images

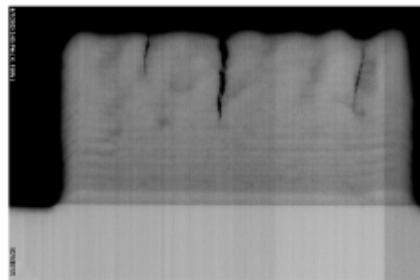


Superalloy (MAR-M247) printing: minimize crack formation by controlling laser power and scan speed

Reality check: grid measurements: X-ray images

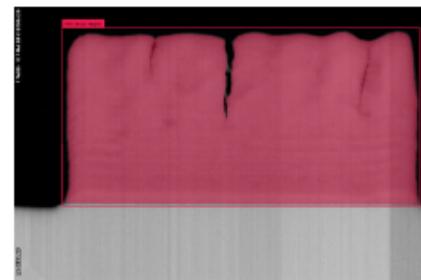


Computer vision workflow for identifying defects from X-ray images and quantify them

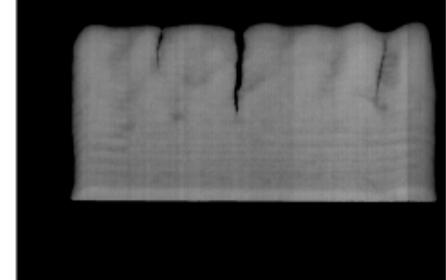


Main object identification

Grounded
DINO + SAM



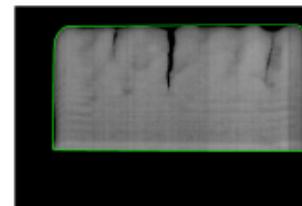
Segmentation



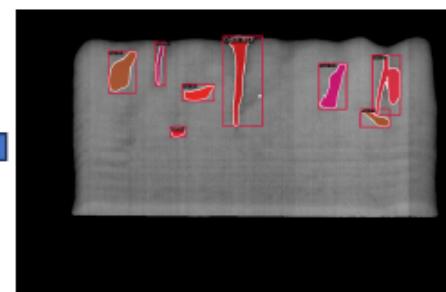
Intensity adjusted
crack area : $\text{sum}(\text{Ic}/\text{Is})$
 Ic : crack pixel intensity
 Is : most frequent non crack pixel
intensity
Measure the amount of materials
is missing.

Compute
Quality

Convex Hull Contour

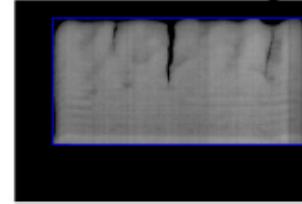


MaskRCNN
Crack
detection



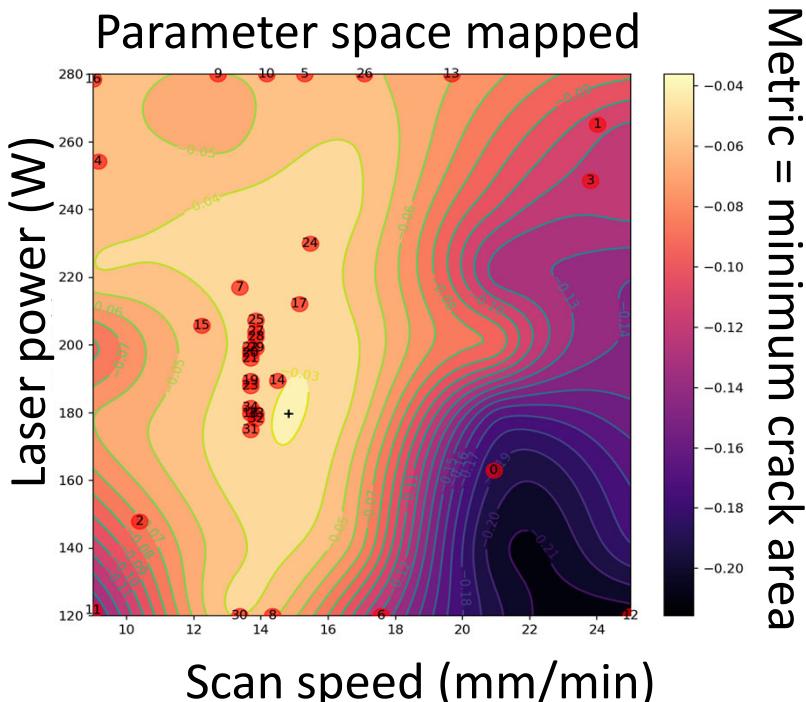
Estimate
sample area

Minimum Bounding Box



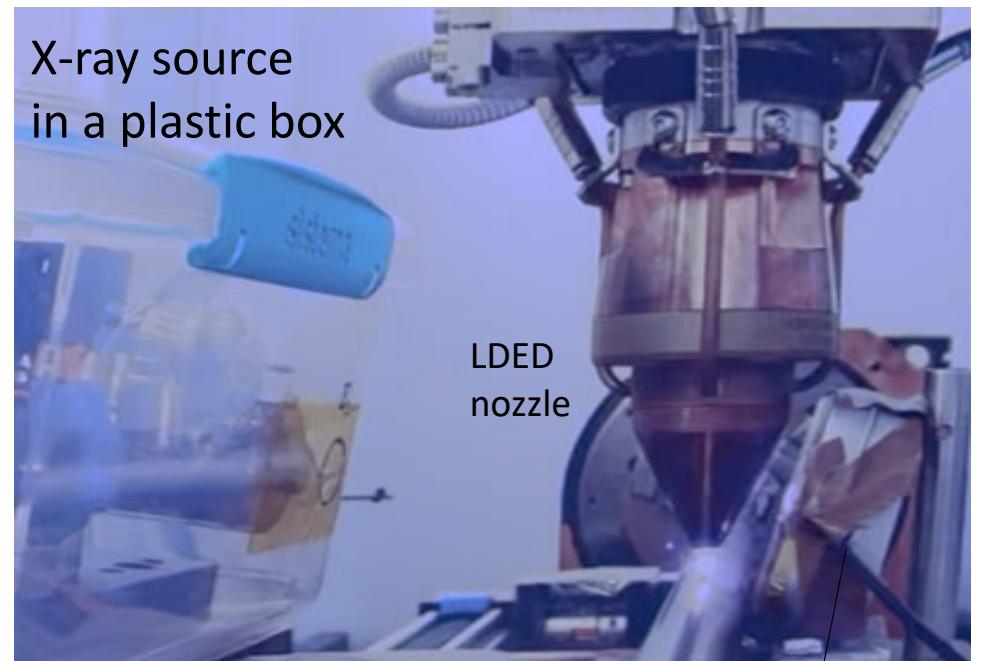
Metric =
Intensity adjusted
crack area/sample area

Demonstration of autonomous metal additive manufacturing



After ~8 prints,
best conditions are identified

→ After 40 min:
the plastic had melted and imager was burned





Summary

We are developing various nimble autonomous materials science platforms

We have demonstrated:

- autonomous control of oxide thin film growth by PLD
(the basis for autonomous semiconductor manufacturing)
- autonomous control of metal additive manufacturing

Acknowledgement

University of Maryland

H. Liang
J.-C. Zhao

Advanced Analyzer

H. Huang

NIST

A. G. Kusne

Univ. of Tokyo

M. Lippmaa
Y. Sun

Supported by NIST, ONR, AFOSR, and SRC

